

AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims:

Claims 1-30. (Canceled).

31. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod-like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of said shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate.

32. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod-like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter

sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when a ~~rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of said shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, and wherein said rod-like electrodes are configured to be connected to wiring so that said electrostatic chuck will be monopole type or bi-pole type.

33. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod-like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when a ~~rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of said shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are

comprised of rod-like base materials, and thermally sprayed films including high-purity ceramics are formed on said rod-like base materials.

34. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod-like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when a ~~rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of said shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are comprised of rod-like base materials, wherein cross-sections of said rod-like base materials are in stepped shapes, and wherein said rod-like electrodes are arranged with a predetermined gap (clearance) between adjacent rod-like electrodes.

35. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod-like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter

sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when a ~~rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are comprised of rod-like base materials, and cross-sections of said rod-like base materials are arranged like roofing tiles, each having a curved convex portion on one side and a curved concave portion on the other side, and wherein each of said convex portions is arranged with a predetermined gap (clearance) between said convex portion and said concave portion of an adjacent rod-like electrode.

36. (Currently Amended) An electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrostatic chuck comprising a plurality of rod-like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when a ~~rectangular~~ the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that

one of said shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are comprised of rod-like base materials, and said rod-like base materials include high-purity isotropic graphite.

37. (Currently Amended) An electrode structure for an electrostatic chuck for electrostatically attracting a rectangular substrate, including a rectangular substrate mounting surface for receiving the rectangular substrate, said electrode structure being comprised of a plurality of rod-like electrodes having shorter sides and longer sides and oriented along the electrostatic chuck in parallel to the substrate mounting surface, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the electrostatic chuck, and longer sides of each of the rod-like electrodes are parallel to longer sides of adjacent rod-like electrodes, wherein the substrate mounting surface and the rod-like electrodes are configured so that, when a rectangular the rectangular substrate is mounted on the substrate mounting surface, the rod-like electrodes will be disposed so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, and

wherein each of the rod-like electrodes includes high-purity ceramic that is thermally sprayed on a surface of rod-like base materials.

38. (Previously Presented) An electrode structure according to claim 37, wherein cross-sections of said base materials are in rectangular shapes.

39. (Previously Presented) An electrode structure according to claim 37, wherein cross-sections of said base materials are in rectangular shapes with wider widths than lengths.

40. (Previously Presented) An electrode structure according to claim 37, wherein cross-sections of said base materials are in stepped shapes.

41. (Previously Presented) An electrode structure according to claim 37, wherein cross-sections of said base materials are arranged like roofing tiles having a curved convex portion on one side and a curved concave portion on the other side.

42. (Previously Presented) An electrode structure according to claim 37, wherein said base materials are comprised of high-purity isotropic graphite.

43. (Currently Amended) A treating system provided with a rectangular substrate stage for receiving a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod-like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when a rectangular the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of the

rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate.

44. (Currently Amended) A treating system provided with a rectangular substrate stage for receiving a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod-like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when a rectangular the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of the rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, and wherein said rod-like electrodes are configured to be connected to wiring so that said rod-like electrodes will be mono-pole or bi-pole type.

45. (Currently Amended) A treating system provided with a rectangular substrate stage for electrostatically attracting a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod-like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are

parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when a ~~rectangular~~ the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of said rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are comprised of rod-like base materials, and wherein thermally sprayed films comprised of high-purity ceramics are formed on surfaces of said rod-like base materials.

46. (Currently Amended) A treating system provided with a rectangular substrate stage for electrostatically attracting a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod-like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when a ~~rectangular~~ the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of said rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrode extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are comprised of rod-like base materials,

wherein cross-sections of said rod-like base materials are in stepped shapes, and wherein said rod-like electrodes are arranged with a predetermined gap (clearance) between adjacent rod-like electrodes.

47. (Currently Amended) A treating system provided with a rectangular substrate stage for electrostatically attracting a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod-like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when a rectangular the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of said rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are comprised of rod-like base materials, wherein cross-sections of said rod-like base materials are arranged like roofing tiles, each having a curved convex portion on one side and a curved concave portion on the other side, and wherein said convex portion is arranged with a predetermined gap (clearance) between said convex portion and said concave portion of an adjacent rod-like electrode.

48. (Currently Amended) A treating system provided with rectangular substrate stage for electrostatically attracting a rectangular substrate, wherein said rectangular substrate stage comprises a plurality of rod-like electrodes each having shorter sides and longer sides and oriented along the rectangular substrate stage, wherein shorter sides of each of said rod-like electrodes are oriented toward outside the rectangular substrate stage; the longer sides of each of the rod-like electrodes are parallel to the longer sides of adjacent rod-like electrodes; and a rectangular substrate is subjected to be electrostatically attracted by the plurality of rod-like electrodes; wherein the rectangular substrate stage and the rod-like electrodes are configured so that, when ~~a rectangular~~ the rectangular substrate is mounted on the rectangular substrate stage, the rod-like electrodes will be disposed along an edge portion of said rectangular substrate to be treated so that one of the shorter sides of each of said rod-like electrodes extends in parallel to a longer side of said rectangular substrate, wherein said rod-like electrodes are comprised of rod-like base materials, and wherein said rod-like base materials include high-purity isotropic graphite.